

Form 1449*	Atty. Docket No.: 303.676US2	Serial No. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Gurtej Singh Sandhu et al.	
	Filing Date: Herewith	Group: Unknown

PTO-17  
08/28/01  
U.S. Patent Office  
98-19407  
98-19408

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Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	4,340,617	07/20/1982	Deutsch, et al.	427	53.1	05/19/80
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	4,713,258	12/15/1987	Umemura	427	35	07/03/85
	4,721,631	01/26/1988	Endo, et al.	427	66	03/09/87
	4,751,101	06/14/1988	Joshi, R.V.	427	39	04/30/87
	4,868,005	09/19/1989	Ehrlich, et al.	427	53.1	03/10/88
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	4,923,717	05/08/1990	Gladfelter, et al.	427	252	03/17/89
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	5,022,905	06/11/1991	Grundy, et al.	65	60.51	10/12/89
	5,032,233	07/16/1991	Yu, C., et al.	204	192.28	09/05/90
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Date Considered

7-5-02

Substitute Disclosure Statement Form (PTO-1449)

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*Milczewski**3/2005*

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**Examiner					Translatio	
Initial	Attachment Number	Date	Country	Class	Subclass	Yes
No						

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(Including Author, Title, Date, Pertinent Pages, Etc.)

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(Including Author, Title, Date, Pertinent Pages, Etc.)

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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)		Complete if Known	
		<b>Application Number</b>	09/940,917
		<b>Filing Date</b>	August 28, 2001
		<b>First Named Inventor</b>	Sandhu, Gurtej
		<b>Group Art Unit</b>	2822
<b>Examiner Name</b>		Wilczewski, Mary	
Sheet 1 of 1		Attorney Docket No: 303.676US2	

US PATENT DOCUMENTS				
Examiner Initial	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Filing Date If Appropriate
TMW	US-5,654,577	08/05/1997	Nakamura, M. , et al.	06/07/1995

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EXAMINER M.Wilczewski DATE CONSIDERED 3/2005

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